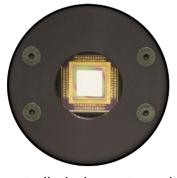
# Low Actuator Count **Deformable Mirrors**

### **Low Actuator Count DMs**

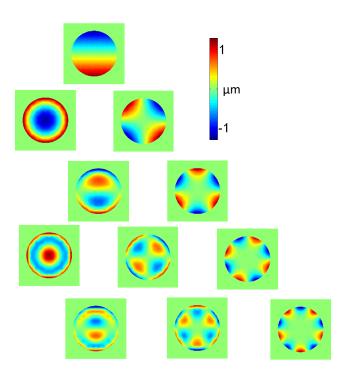
Low-actuator count DM systems are economic and versatile solutions for advanced wavefront control, coming in the form of the Multi-DM.



With up to 140 precisely controlled elements and low inter-actuator coupling, the Multi-DM system is ideal for a broad range of applications including microscopy, astronomy, retinal imaging, and laser beam shaping. This DM is available in both continuous and segmented surfaces for adaptive optics or spatial light modulator applications.

The Multi-DM is capable of up to 5.5 µm stroke, 8 kHz frame rate, have sub-nm step size, and no hysteresis.

## **Demonstrated High Order Aberration Correction**



High speed electronic upgrades are available for Measured Zernikes: >130 actuators with low interactuator the Multi-DM systems, in the form of the X-Driver. coupling create high order Zernike modes

#### **DM Properties**

Mirror Coating: Aluminum, Gold or Protected Silver					
Window:	AR coatings available				
Hysteresis:	None				
Step size:	Sub-nm (average)				
Surface Type:	Continuous (DM), Segmented (SLM)				
Fill Factor:	>99%				
Surface Figure:<30nm RMS					

## **Driver Specifications**

Dimensions:	9" x 7" x 2.5"
Interface:	USB 2.0
Input Voltage:	100-240V AC
Resolution:	14 bit
Frame Rate:	8 kHz*



Specifications*	Total Actuator Count	Actuator Count Across Aperture	Stroke (µm)	Aperture (mm)	Pitch (µm)	Mechanical Response (10% - 90%)	Approximate Interactuator Coupling	Price**
Multi-C-1.5	137	13	1.5	3.6	300	<40 µs	15%	\$12,000
Multi-3.5	140	12	3.5	4.4	400	<75 µs	13%	\$17,900
Multi-3.5L	140	12	3.5	4.9	450	<75 μs	13%	\$20,900
Multi-5.5	140	12	5.5	4.95	450	<100 µs	22%	Upon Request
Multi-SLM <sup>†</sup>	140	12	1.5	3.6	300	<35 µs	0%	Upon Request

<sup>\*</sup>High speed driver options are available.

†Segmented surface mirror. All other configurations have continuous surfaces.

\*\*Includes mirror, driver and operational software